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# VACUUM CHAMBER PM TECHNIQUE LAM 9600 PTX METAL ETCH CHAMBER CLEAN

#### **OBJECTIVE**:

TO EFFECTIVELY PM THE METAL ETCH CHAMBER IN A TIMELY MANNER, WHILE IMPROVING TOOL RECOVERY AND PARTICLE PERFORMANCE

<u>Vacuum Chamber</u>: LAM METAL ETCHER (\*\*THIS TECHNIQUE IS A

SIMILAR METHOD USED FOR OTHER ETCH TOOLS)

<u>Vacuum Chamber Process Residue</u>: PROCESS INDUCED RESIDUE

<u>Vacuum Chamber Components</u>: METAL ETCH CHAMBER AND CHAMBER LID

Old Procedure: ScotchBrite<sup>®</sup>, 40 grit sand paper, wire mesh, scrapers, IPA and

**Texwipes** 

Some facilities are not able to clean Metal Etch Chamber due to

the fact that the current method is not very effective

**Solvent:** DI water, IPA (only)

<u>Time:</u> After initial clean is completed down to bare metal (see pictures

below), future cleans take less than 20 minutes

# **Vacuum Chamber Products:**

- (1) HT4754 UltraSOLV® Sponge
- (1) HT4528D-10 280 Grit Diamond ScrubPAD\*\*
- (1) HT4580D-10 800 Grit Diamond ScrubPAD
- (5) <u>HT179028D</u> 280 ScrubTIP<sup>®</sup> \*\* (for the removal of hardened deposition from corners and tracks)
- (5) HT1000 CleanWIPE® Swab
- (1) HT5790S-25 MiraWIPE® Wipers

Most PM's can be performed with 280 or 360 grit pads but the use of more aggressive pads may be required for certain processes or on the first PM that takes the tool down to bare metal.

<sup>\*\*</sup>Various diamond grit abrasives can be selected for this process depending on the amount of deposition build-up within the Metal Etch Chamber – Range from 140 to 800 diamond grit available.

#### **METAL ETCH CHAMBER CLEAN:**

View "How to" instructional videos on http://www.foamtecintlwcc.com/flash/

- Step 1: Remove all necessary parts from within Metal Etch Chamber
- Step 2: Thoroughly wipe-down inside of the chamber using a DI water dampened UltraSOLV® <u>HT4754</u> Sponge. This will be necessary to remove any flaking or large deposits that would unnecessarily load up the ScrubPADs
- **Step 3:** Using a DI water dampened <u>HT4528D</u>-10 ScrubPAD, scrub a 5"x5" area within the Metal Etch Chamber
- **Step 4:** Wipe-down the affected chamber area using the DI water dampened UltraSOLV<sup>®</sup> HT4754 Sponge
- **Step 5:** Unload the ScrubPAD of deposition by wiping the UltraSOLV<sup>®</sup> HT4754 Sponge with the ScrubPAD in one direction (See Fig 1, 2 & 3)

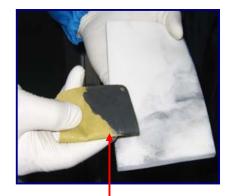


Fig 1: ScrubPAD loaded with deposition water

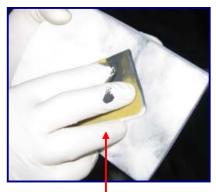


Fig 2: Pull ScrubPAD across a damp UltraSOLV® Sponge

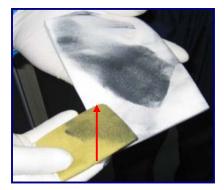


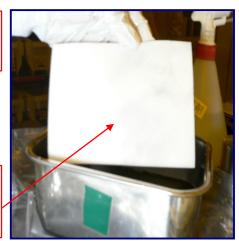
Fig 3: Unloaded ScrubPAD

**Step 6:** Unload the UltraSOLV<sup>®</sup> <u>HT4754</u> Sponge by moistening with DI water and ringing out into a HazMat container (See Fig 4 & 5)



Fig 4: UltraSOLV® Sponge loaded with deposition





#### METAL ETCH CHAMBER PM PROCEDURE (CONT'D):

- **Step 7:** Repeat steps 3 5, using the <u>HT4528D</u> ScrubPAD and the <u>HT179028D</u> ScrubTIP<sup>®</sup> where necessary, until all deposition is removed
- Step 8: After effectively cleaning the Metal Etch Chamber use the <a href="https://htt

## **FINAL WIPE PROCEDURE:**

## **IMPORTANT NOTE**

THE USE OF <u>HT5790S</u> MIRAWIPES® DURING FINAL WIPE PORTION OF PROCEDURE IS A CRITICAL STEP TO EFFECTIVELY REMOVING PARTICLE DEFECTS

NOTE: Figure below shows how much more deposition the Foamtec International MiraWIPE® can remove from a critical surface compared to the standard fab wiper, making the MiraWIPE® FINAL WIPE PROCEDURE the most CRITICAL STEP of the PM procedure (See Fig 6a & 6b)

Fig 6a: What the MiraWIPE® was able to remove, AFTER the standard fab wiper



Fig 6b: The last standard fab wiper used to wipe the

MiraWIPES® are the <u>KEY STEP</u> for <u>DEFECT</u>
REDUCTION and IMPROVED TOOL RECOVERY

Step 9: Repeatedly wipe the inside of the Metal Etch Chamber using an IPA dampened <a href="https://example.com/HT5790S"><u>HT5790S</u></a> MiraWIPE<sup>®</sup>. Dampen the <a href="https://example.com/HT1000"><u>HT1000</u></a> CleanWIPE<sup>®</sup> Swab and effectively remove any deposition left in the hard to reach areas. Ensure to wipe entire chamber effectively until all areas are cleaned of deposition

# Metal Etch Chamber - Pre-Clean





Metal Etch Chamber - Post-Clean





